

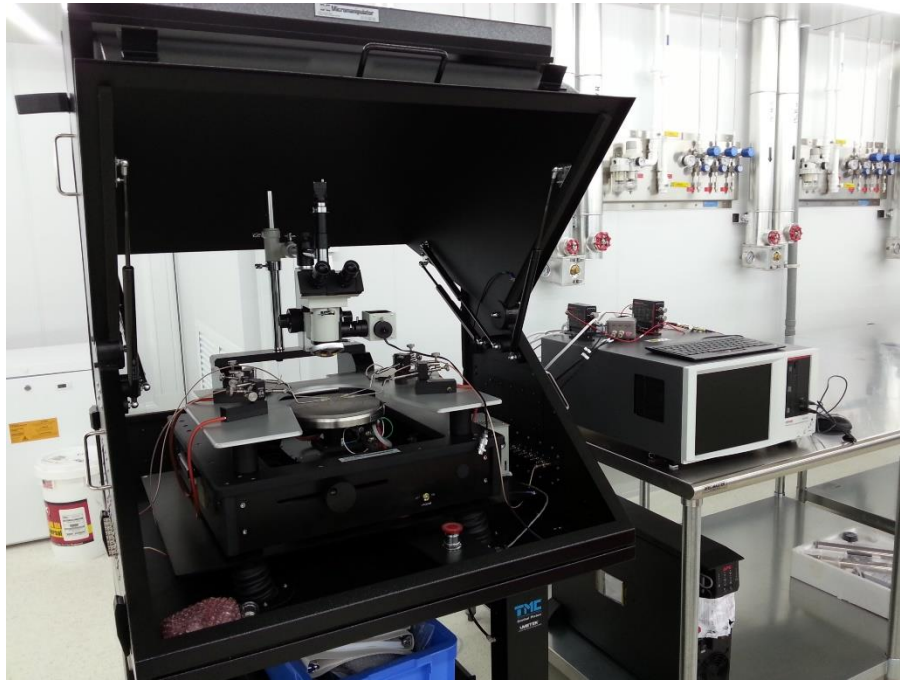
UMF Equipment – Probe Station with Semiconductor Parameter Analyzer

Micromanipulator 450PM

A probe station is used to physically acquire signals from the internal nodes of a semiconductor device. The probe station utilizes manipulators which allow the precise positioning of thin needles on the surface of a semiconductor device. If the device is being electrically stimulated, the signal is acquired by the probe and forwarded to analyzer. The probe station is often used in the failure analysis of semiconductor devices.

- Features:
- Substrate size: Up to 6" wafer
 - Magnification Power: 0.7 → 4.5X, 10X eyepiece
 - Aluminum platen: Fixed and stable
 - Thermal chuck: max. 400°C
 - Measurement: DC I-V, C-V, pulse and ultra-fast I-V testing

Please refer to supplier information page: <https://www.micromanipulator.com/> for further details of the system.
For any inquiry, please contact Dr. Terence Wong (Tel: 3400 2075; Email: tai-lun.wong@polyu.edu.hk).



Micromanipulator 450PM Probe Station